

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:
John L. Klocke and Linlin Chen
Application No. 10/688,420
Filed: October 16, 2003
Confirmation No. Not yet assigned
For: ELECTROPLATING COMPOSITIONS AND METHODS FOR ELECTROPLATING
Examiner: Not yet assigned
Art Unit: Not yet assigned
Attorney Reference No. 6884-65576

CERTIFICATE OF MAILING

I hereby certify that this paper and the documents referred to as being attached or enclosed herewith are being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: COMMISSIONER FOR PATENTS, P.O. BOX 1450, ALEXANDRIA, VA 22313-1450 on the date shown below.

Attorney for Applicant(s) _____

Date Mailed 1/22/04

INFORMATION DISCLOSURE STATEMENT
PURSUANT TO 37 C.F.R. § 1.97(b)(3)

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Listed on the accompanying form PTO-1449 and enclosed herewith are several English-language documents. Applicants respectfully request that these documents be listed as references cited on the issued patent.

Applicants filed this Information Disclosure Statement ("IDS") before the mailing date of a first Office action on the merits. As a result, no fee should be required to file this IDS. However, if the Patent Office determines that a fee is required for Applicants to file this IDS, please charge any such fees, or credit overpayment, to Deposit Account No. 02-4550. A **duplicate** copy of this Information Disclosure Statement is enclosed.

The filing of this IDS shall not be construed to be an admission that the information cited in the statement is, or is considered to be, prior art or otherwise material to patentability as defined in 37 C.F.R. §1.56.

Respectfully submitted,

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First Named Inventor	John L. Klocke
Art Unit	Not yet assigned
Examiner Name	Not yet assigned

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

U.S. PATENT DOCUMENTS

Examiner's Initials*	Cite No. (optional)	Number	Date	Name
		5,972,192	10/1999	Dubin et al.
		6,074,544	6/2000	Reid et al.
		6,290,833	9/2001	Chen
		6,331,490	12/2001	Stevens et al.
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		6,508,920	1/2003	Ritzdorf et al.
		6,517,894	2/2003	Hongo et al.
		6,534,117	3/2003	Yoshio et al.
		6,565,729	5/2003	Chen et al.
		US 2002/0112964	8/2002	Gandikota et al.
		US 2004/0007467	1/2004	McHugh et al.

FOREIGN PATENT DOCUMENTS

Examiner's Initials*	Cite No. (optional)	Number	Date	Country

EXAMINER SIGNATURE:	DATE CONSIDERED:

* Examiner: Initial if reference considered, whether or not in conformance with MPEP 609. Draw line through cite if not in conformance and not considered. Include copy of this form with next communication to applicant.

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Examiner's Initials*	Cite No. (optional)	OTHER DOCUMENTS
		Dordi, Yezdi et al., "Automated Chemical Management for Production Copper Electroplating," *Semiconductor Fabtech - 11th Edition*, 273-276.
		Lin, Xuan et al., "Chemistry for the 0.13μm copper interconnect process," Ethone OMI, publication date unknown.

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